Dzung Viet Dao

List of Publications by Year in Descending Order

263 papers	3,759 citations	33 h-index	46 g-index
324 ext. papers	4,672 ext. citations	4 avg, IF	5.85 L-index

#	Paper	IF	Citations
263	Noninvasive refilling of liquid marbles with water for microfluidic applications. *Applied Physics Letters*, **2022**, 120, 064102	3.4	0
262	The concept of light-harvesting, self-powered mechanical sensors using a monolithic structure. *Nano Energy*, **2022**, 107030	17.1	0
261	Reduced graphene oxide nanofluidic electrolyte with improved electrochemical properties for vanadium flow batteries. *Journal of Energy Storage*, **2022**, 49, 104133	7.8	1
260	Biosensors and Chemical Sensors for Healthcare Monitoring: A Review. *IEEJ Transactions on Electrical and Electronic Engineering*, **2022**, 17, 626-636	1	4
259	Enhanced Electrohydrodynamics for Electrospinning a Highly Sensitive Flexible Fiber-Based Piezoelectric Sensor. *ACS Applied Electronic Materials*, **2022**, 4, 1301-1310	4	4
258	Low-Dimensional Palladium on Graphite-on-Paper Substrate for Hydrogen Sensing. *Sensors*, **2022**, 22, 3926	3.8	
257	Generation of a Charge Carrier Gradient in a 3C-SiC/Si Heterojunction with Asymmetric Configuration. *ACS Applied Materials & Interfaces*, **2021**, 13, 55329-55338	9.5	2
256	A Wearable, Bending-Insensitive Respiration Sensor Using Highly Oriented Carbon Nanotube Film. *IEEE Sensors Journal*, **2021**, 21, 7308-7315	4	5
255	Effects of photogenerated-hole diffusion on 3C-SiC/Si heterostructure optoelectronic position-sensitive detector. *Journal Physics D: Applied Physics*, **2021**, 54, 265101	3	3
254	Electrospray propelled by ionic wind in a bipolar system for direct delivery of charge reduced nanoparticles. *Applied Physics Express*, **2021**, 14, 055001	2.4	1
253	AlGaN/GaN 2-D Electron Gas for Highly Sensitive and High-Temperature Current Sensing. *IEEE Transactions on Electron Devices*, **2021**, 68, 1495-1500	2.9	2
252	Piezotronic effect in a normally off p-GaN/AlGaN/GaN HEMT toward highly sensitive pressure sensor. *Applied Physics Letters*, **2021**, 118, 242104	3.4	3
251	Advances in Si and SiC Materials for High-Performance Supercapacitors toward Integrated Energy Storage Systems. *Small*, **2021**, 17, e2101775	11	4
250	Natural fiber□einforced composites: A review on material, manufacturing, and machinability. *Journal of Thermoplastic Composite Materials*, **2021**, 34, 238-284	1.9	86
249	Wet oxidation of 3C-SiC on Si for MEMS processing and use in harsh environments: Effects of the film thicknesses, crystalline orientations, and growth temperatures. *Sensors and Actuators A: Physical*, **2021**, 317, 112474	3.9	1
248	Ultra-sensitive self-powered position-sensitive detector based on horizontally-aligned double 3C-SiC/Si heterostructures. *Nano Energy*, **2021**, 79, 105494	17.1	10
247	Physical Sensors: Thermal Sensors **2021**,		0

246	Advances in ultrasensitive piezoresistive sensors: from conventional to flexible and stretchable applications. *Materials Horizons*, **2021**, 8, 2123-2150	14.4	9
245	In-air particle generation by on-chip electrohydrodynamics. *Lab on A Chip*, **2021**, 21, 1779-1787	7.2	1
244	Piezoresistive Effect with a Gauge Factor of 18 000 in a Semiconductor Heterojunction Modulated by Bonded Light-Emitting Diodes. *ACS Applied Materials & Interfaces*, **2021**, 13, 35046-35053	9.5	3
243	Transient start-up of an electric swashplate refrigeration compressor. *Applied Thermal Engineering*, **2021**, 196, 117351	5.8	0
242	Thermo-electro-rheological behaviour of vanadium electrolyte-based electrochemical graphene oxide nanofluid designed for redox flow battery. *Journal of Molecular Liquids*, **2021**, 338, 116860	6	8
241	Pressure and temperature sensitive e-skin for in situ robotic applications. *Materials and Design*, **2021**, 208, 109886	8.1	8
240	Optothermotronic effect as an ultrasensitive thermal sensing technology for solid-state electronics. *Science Advances*, **2020**, 6, eaay2671	14.3	9
239	Optoelectronic Enhancement for Piezoresistive Pressure Sensor **2020**,		2
238	Real gas model for an electric swashplate refrigeration compressor. *International Journal of Refrigeration*, **2020**, 118, 210-219	3.8	1
237	Core-Shell Beads Made by Composite Liquid Marble Technology as A Versatile Microreactor for Polymerase Chain Reaction. *Micromachines*, **2020**, 11,	3.3	25
236	Opto-electronic coupling in semiconductors: towards ultrasensitive pressure sensing. *Journal of Materials Chemistry C*, **2020**, 8, 4713-4721	7.1	12
235	Highly-doped SiC resonator with ultra-large tuning frequency range by Joule heating effect. *Materials and Design*, **2020**, 194, 108922	8.1	4
234	Self-powered monolithic accelerometer using a photonic gate. *Nano Energy*, **2020**, 76, 104950	17.1	11
233	Palladium on paper as a low-cost and flexible material for fast hydrogen sensing. *Journal of Materials Science: Materials in Electronics*, **2020**, 31, 5298-5304	2.1	5
232	Advances in Rational Design and Materials of High-Performance Stretchable Electromechanical Sensors. *Small*, **2020**, 16, e1905707	11	22
231	Charge reduced nanoparticles by sub-kHz ac electrohydrodynamic atomization toward drug delivery applications. *Applied Physics Letters*, **2020**, 116, 023703	3.4	5
230	Lithography and Etching-Free Microfabrication of Silicon Carbide on Insulator Using Direct UV Laser Ablation . *Advanced Engineering Materials*, **2020**, 22, 1901173	3.5	4
229	High temperature silicon-carbide-based flexible electronics for monitoring hazardous environments. *Journal of Hazardous Materials*, **2020**, 394, 122486	12.8	12

228	Critical Trapping Conditions for Floating Liquid Marbles. *Physical Review Applied*, **2020**, 13,	4.3	14
227	A new structure of Tesla coupled nozzle in synthetic jet micro-pump. *Sensors and Actuators A: Physical*, **2020**, 315, 112296	3.9	7
226	Advances in electrode and electrolyte improvements in vanadium redox flow batteries with a focus on the nanofluidic electrolyte approach. *Physics Reports*, **2020**, 881, 1-49	27.7	16
225	Stretchable respiration sensors: Advanced designs and multifunctional platforms for wearable physiological monitoring. *Biosensors and Bioelectronics*, **2020**, 166, 112460	11.8	59
224	Analytical and experimental investigation of the parameters in drilling flax/poly(lactic acid) bio-composite laminates. *International Journal of Advanced Manufacturing Technology*, **2020**, 109, 503-521	3.2	2
223	Drilling Behavior of Flax/Poly(Lactic Acid) Bio-Composite Laminates: An Experimental Investigation. *Journal of Natural Fibers*, **2020**, 17, 1264-1280	1.8	9
222	Paper-Based Electronics Using Graphite and Silver Nanoparticles for Respiration Monitoring. *IEEE Sensors Journal*, **2019**, 19, 11784-11790	4	18
221	Ultra-Sensitive OPTO-Piezoresistive Sensors Utilising 3C-SiC/Si Heterostructures **2019**,		2
220	Giant piezoresistive effect by optoelectronic coupling in a heterojunction. *Nature Communications*, **2019**, 10, 4139	17.4	28
219	3C-SiC/Si Heterostructure: An Excellent Platform for Position-Sensitive Detectors Based on Photovoltaic Effect. *ACS Applied Materials & Interfaces*, **2019**, 11, 40980-40987	9.5	28
218	Thermoresistance of p-Type 4H-SiC Integrated MEMS Devices for High-Temperature Sensing. *Advanced Engineering Materials*, **2019**, 21, 1801049	3.5	7
217	A hot-film air flow sensor for elevated temperatures. *Review of Scientific Instruments*, **2019**, 90, 015007	1.7	10
216	Numerical simulation of combined natural and thermomagnetic convection around a current carrying wire in ferrofluid. *Journal of Magnetism and Magnetic Materials*, **2019**, 489, 165383	2.8	11
215	Accurate dielectrophoretic positioning of a floating liquid marble with a two-electrode configuration. *Microfluidics and Nanofluidics*, **2019**, 23, 1	2.8	13
214	Transparent crystalline cubic SiC-on-glass electrodes enable simultaneous electrochemistry and optical microscopy. *Chemical Communications*, **2019**, 55, 7978-7981	5.8	2
213	Soft ionic liquid multi-point touch sensor.. *RSC Advances*, **2019**, 9, 10733-10738	3.7	4
212	An automated on-demand liquid marble generator based on electrohydrodynamic pulling. *Review of Scientific Instruments*, **2019**, 90, 055102	1.7	13
211	Apparent thermal conductivity of photoluminescent C-dot nanofluid. *Journal of Molecular Liquids*, **2019**, 286, 110948	6	2

210	Dielectrophoretic Trapping of a Floating Liquid Marble. *Physical Review Applied*, **2019**, 11,	4.3	22
209	Polyacrylonitrile-carbon Nanotube-polyacrylonitrile: A Versatile Robust Platform for Flexible Multifunctional Electronic Devices in Medical Applications. *Macromolecular Materials and Engineering*, **2019**, 304, 1900014	3.9	11
208	Self-Powered Broadband (UV-NIR) Photodetector Based on 3C-SiC/Si Heterojunction. *IEEE Transactions on Electron Devices*, **2019**, 66, 1804-1809	2.9	24
207	Palladium microfiber network as a platform for hydrogen sensing applications. *Journal of Physics and Chemistry of Solids*, **2019**, 131, 50-54	3.9	3
206	Dependence of offset voltage in AlGaN/GaN van der Pauw devices under mechanical strain. *Materials Letters*, **2019**, 244, 66-69	3.3	2
205	Wireless Battery-Free SiC Sensors Operating in Harsh Environments Using Resonant Inductive Coupling. *IEEE Electron Device Letters*, **2019**, 40, 609-612	4.4	11
204	Liquid marbles as biochemical reactors for the polymerase chain reaction. *Lab on A Chip*, **2019**, 19, 3220-3227	7.2	31
203	Long-Lived, Transferred Crystalline Silicon Carbide Nanomembranes for Implantable Flexible Electronics. *ACS Nano*, **2019**, 13, 11572-11581	16.7	65
202	Palladium Nanofiber Networks Hydrogen Sensor and Hydrogen-Actuated Switches. *Smart Innovation, Systems and Technologies*, **2019**, 116-125	0.5	1
201	Low-Cost Multifunctional Ionic Liquid Pressure and Temperature Sensor. *Smart Innovation, Systems and Technologies*, **2019**, 184-192	0.5	2
200	Carbon Nanotube Four-Terminal Devices for Pressure Sensing Applications. *Smart Innovation, Systems and Technologies*, **2019**, 199-207	0.5	1
199	Ultraviolet and Visible Photodetection Using 3C-SiC/Si Hetero-Epitaxial Junction. *Smart Innovation, Systems and Technologies*, **2019**, 208-216	0.5	1
198	Effect of Drilling Parameters on Delamination and Hole Quality in Drilling Flax Fiber Reinforced Bio-Composites. *Smart Innovation, Systems and Technologies*, **2019**, 71-81	0.5	3
197	Demodulation Band Optimization in Envelope Analysis for Fault Diagnosis of Rolling Element Bearings Using a Real-Coded Genetic Algorithm. *IEEE Access*, **2019**, 7, 168828-168838	3.5	6
196	Onset of thermomagnetic convection around a vertically oriented hot-wire in ferrofluid. *Journal of Magnetism and Magnetic Materials*, **2018**, 456, 300-306	2.8	15
195	Electrical Resistance of Carbon Nanotube Yarns Under Compressive Transverse Pressure. *IEEE Electron Device Letters*, **2018**, 39, 584-587	4.4	12
194	Unintentionally Doped Epitaxial 3C-SiC(111) Nanothin Film as Material for Highly Sensitive Thermal Sensors at High Temperatures. *IEEE Electron Device Letters*, **2018**, 39, 580-583	4.4	17
193	Liquid marble coalescence via vertical collision. *Soft Matter*, **2018**, 14, 4160-4168	3.6	30

192	Highly sensitive p-type 4H-SiC van der Pauw sensor.. *RSC Advances*, **2018**, 8, 3009-3013	3.7	15
191	Robust Free-Standing Nano-Thin SiC Membranes Enable Direct Photolithography for MEMS Sensing Applications. *Advanced Engineering Materials*, **2018**, 20, 1700858	3.5	18
190	A Generalized Analytical Model for Joule Heating of Segmented Wires. *Journal of Heat Transfer*, **2018**, 140,	1.8	6
189	A rapid and cost-effective metallization technique for 3C-SiC MEMS using direct wire bonding.. *RSC Advances*, **2018**, 8, 15310-15314	3.7	5
188	Degraded boiling heat transfer from hotwire in ferrofluid due to particle deposition. *Applied Thermal Engineering*, **2018**, 142, 255-261	5.8	10
187	Photoresponse of a Highly-Rectifying 3C-SiC/Si Heterostructure Under UV and Visible Illuminations. *IEEE Electron Device Letters*, **2018**, 39, 1219-1222	4.4	10
186	High-temperature tolerance of the piezoresistive effect in p-4H-SiC for harsh environment sensing. *Journal of Materials Chemistry C*, **2018**, 6, 8613-8617	7.1	20
185	Isotropic piezoresistance of p-type 4H-SiC in (0001) plane. *Applied Physics Letters*, **2018**, 113, 012104	3.4	19
184	Highly sensitive 4H-SiC pressure sensor at cryogenic and elevated temperatures. *Materials and Design*, **2018**, 156, 441-445	8.1	39
183	Development of PZT Actuated Valveless Micropump. *Sensors*, **2018**, 18,	3.8	37
182	Evaporation dynamics of liquid marbles at elevated temperatures.. *RSC Advances*, **2018**, 8, 15436-15443	3.7	30
181	Characterization of the piezoresistance in highly doped p-type 3C-SiC at cryogenic temperatures.. *RSC Advances*, **2018**, 8, 29976-29979	3.7	6
180	An On-Chip SiC MEMS Device with Integrated Heating, Sensing, and Microfluidic Cooling Systems. *Advanced Materials Interfaces*, **2018**, 5, 1800764	4.6	26
179	Utilizing large hall offset voltage for conversion free 4H-SiC strain sensor **2018**,		1
178	Highly sensitive 3C-SiC on glass based thermal flow sensor realized using MEMS technology. *Sensors and Actuators A: Physical*, **2018**, 279, 293-305	3.9	22
177	Highly sensitive pressure sensors employing 3C-SiC nanowires fabricated on a free standing structure. *Materials and Design*, **2018**, 156, 16-21	8.1	30
176	Impact of Design and Process on Performance of SiC Thermal Devices. *SpringerBriefs in Applied Sciences and Technology*, **2018**, 75-83	0.4	
175	Fabrication of SiC MEMS Sensors. *SpringerBriefs in Applied Sciences and Technology*, **2018**, 55-74	0.4	

174	Fundamentals of Thermoelectrical Effect in SiC. *SpringerBriefs in Applied Sciences and Technology*, **2018**, 11-41	0.4	1
173	Desirable Features for High-Temperature SiC Sensors. *SpringerBriefs in Applied Sciences and Technology*, **2018**, 43-53	0.4	2
172	Applications of Thermoelectrical Effect in SiC. *SpringerBriefs in Applied Sciences and Technology*, **2018**, 85-106	0.4	
171	Introduction to SiC and Thermoelectrical Properties. *SpringerBriefs in Applied Sciences and Technology*, **2018**, 1-9	0.4	0
170	Future Prospects of SiC Thermoelectrical Sensing Devices. *SpringerBriefs in Applied Sciences and Technology*, **2018**, 107-115	0.4	
169	Silicon Micro-/Nanomachining and Applications **2018**, 225-261		1
168	A large pseudo-Hall effect in n-type 3C-SiC(1 0 0) and its dependence on crystallographic orientation for stress sensing applications. *Materials Letters*, **2018**, 213, 11-14	3.3	8
167	Digital polymerase chain reaction technology - recent advances and future perspectives. *Lab on A Chip*, **2018**, 18, 3717-3732	7.2	59
166	Integrated photonic platform for quantum information with continuous variables. *Science Advances* , **2018**, 4, eaat9331	14.3	60
165	Strain Effect in Highly-Doped n-Type 3C-SiC-on-Glass Substrate for Mechanical Sensors and Mobility Enhancement. *Physica Status Solidi (A) Applications and Materials Science*, **2018**, 215, 1800288	1.6	4
164	Low-Cost Graphite on Paper Pressure Sensor for a Robot Gripper with a Trivial Fabrication Process. *Sensors*, **2018**, 18,	3.8	9
163	Thermoelectrical Effect in SiC for High-Temperature MEMS Sensors. *SpringerBriefs in Applied Sciences and Technology*, **2018**,	0.4	1
162	Optical and Electrical Characterizations of Nanoscale Robust 3C-SiC Membrane for UV Sensing Applications. *Key Engineering Materials*, **2018**, 775, 278-282	0.4	
161	Environment-friendly wearable thermal flow sensors for noninvasive respiratory monitoring **2017**,		5
160	Active demultiplexing of single photons from a solid-state source. *Laser and Photonics Reviews*, **2017**, 11, 1600297	8.3	35
159	Formation of silicon carbide nanowire on insulator through direct wet oxidation. *Materials Letters*, **2017**, 196, 280-283	3.3	3
158	Solvent-free fabrication of biodegradable hot-film flow sensor for noninvasive respiratory monitoring. *Journal Physics D: Applied Physics*, **2017**, 50, 215401	3	39
157	Experimental Investigation of Piezoresistive Effect in p-Type 4H-SiC. *IEEE Electron Device Letters*, **2017**, 38, 955-958	4.4	33

156	Thermomagnetic Convection Around a Current-Carrying Wire in Ferrofluid. *Journal of Heat Transfer*, **2017**, 139,	1.8	12
155	Ultra-high strain in epitaxial silicon carbide nanostructures utilizing residual stress amplification. *Applied Physics Letters*, **2017**, 110, 141906	3.4	17
154	Steady-state analytical model of suspended p-type 3C-SiC bridges under consideration of Joule heating. *Journal of Micromechanics and Microengineering*, **2017**, 27, 075008	2	9
153	Piezo-Hall effect and fundamental piezo-Hall coefficients of single crystal n-type 3C-SiC(100) with low carrier concentration. *Applied Physics Letters*, **2017**, 110, 162903	3.4	3
152	. *Journal of Microelectromechanical Systems*, **2017**, 26, 966-986	2.5	78
151	Pseudo-Hall Effect in Single Crystal n-Type 3C-SiC(100) Thin Film. *Key Engineering Materials*, **2017**, 733, 3-7	0.4	3
150	Self-sensing paper-based actuators employing ferromagnetic nanoparticles and graphite. *Applied Physics Letters*, **2017**, 110, 144101	3.4	18
149	Hydrogen sensor based on palladium-yttrium alloy nanosheet. *Materials Chemistry and Physics*, **2017**, 194, 231-235	4.4	19
148	Single-Crystalline 3C-SiC anodically Bonded onto Glass: An Excellent Platform for High-Temperature Electronics and Bioapplications. *ACS Applied Materials & Interfaces*, **2017**, 9, 27365-27371	9.5	41
147	Superior Robust Ultrathin Single-Crystalline Silicon Carbide Membrane as a Versatile Platform for Biological Applications. *ACS Applied Materials & Interfaces*, **2017**, 9, 41641-41647	9.5	13
146	Pushing the Limits of Piezoresistive Effect by Optomechanical Coupling in 3C-SiC/Si Heterostructure. *ACS Applied Materials & Interfaces*, **2017**, 9, 39921-39925	9.5	22
145	Electrically Stable Carbon Nanotube Yarn Under Tensile Strain. *IEEE Electron Device Letters*, **2017**, 38, 1331-1334	4.4	13
144	Excellent Rectifying Properties of the n-3C-SiC/p-Si Heterojunction Subjected to High Temperature Annealing for Electronics, MEMS, and LED Applications. *Scientific Reports*, **2017**, 7, 17734	4.9	30
143	Fabrication of a sensitive pressure sensor using carbon nanotube micro-yarns **2017**,		1
142	Coalescence Processes of Droplets and Liquid Marbles. *Micromachines*, **2017**, 8,	3.3	33
141	Thermal Flow Sensors for Harsh Environments. *Sensors*, **2017**, 17,	3.8	40
140	Pseudo-Hall Effect in Graphite on Paper Based Four Terminal Devices for Stress Sensing Applications. *Journal of Physics: Conference Series*, **2017**, 829, 012004	0.3	0
139	Vibration analysis of initially curved single walled carbon nanotube with vacancy defect for ultrahigh frequency nanoresonators. *Microsystem Technologies*, **2016**, 22, 1115-1120	1.7	8

138	High Power and Reliable SPST/SP3T RF MEMS Switches for Wireless Applications. *IEEE Electron Device Letters*, **2016**, 37, 1219-1222	4.4	15
137	Piezoresistive effect in p-type 3C-SiC at high temperatures characterized using Joule heating. *Scientific Reports*, **2016**, 6, 28499	4.9	47
136	The Piezoresistive Effect in Top-Down Fabricated p-Type 3C-SiC Nanowires. *IEEE Electron Device Letters*, **2016**, 37, 1029-1032	4.4	41
135	Piezo-Hall effect in single crystal p-type 3C-SiC(100) thin film grown by low pressure chemical vapor deposition. *RSC Advances*, **2016**, 6, 31191-31195	3.7	9
134	Piezoresistive effect of p-type single crystalline 3C-SiC on (111) plane. *RSC Advances*, **2016**, 6, 21302-21307	3.7	31
133	Influence of gallium ion beam acceleration voltage on the bend angle of amorphous silicon cantilevers. *Japanese Journal of Applied Physics*, **2016**, 55, 06GL02	1.4	6
132	Combination Effect of Waviness and Vacancy Defects on the Natural Frequency of Single Walled Carbon Nanotubes. *Journal of Computational and Theoretical Nanoscience*, **2016**, 13, 5031-5036	0.3	0
131	Novel Low-Cost Sensor for Human Bite Force Measurement. *Sensors*, **2016**, 16,	3.8	13
130	A single-layer micromachined tunable capacitor with an electrically floating plate. *Smart Materials and Structures*, **2016**, 25, 045014	3.4	3
129	Fundamental piezo-Hall coefficients of single crystal p-type 3C-SiC for arbitrary crystallographic orientation. *Applied Physics Letters*, **2016**, 109, 092903	3.4	3
128	Nano strain-amplifier: Making ultra-sensitive piezoresistance in nanowires possible without the need of quantum and surface charge effects. *Applied Physics Letters*, **2016**, 109, 123502	3.4	33
127	Floating mechanism of a small liquid marble. *Scientific Reports*, **2016**, 6, 21777	4.9	36
126	Measuring the Coefficient of Friction of a Small Floating Liquid Marble. *Scientific Reports*, **2016**, 6, 38346	4.9	20
125	Experimental investigation of resonant MEMS switch with ac actuation. *Applied Physics Letters*, **2016**, 108, 253501	3.4	2
124	Evaporation of Ethanol-Water Binary Mixture Sessile Liquid Marbles. *Langmuir*, **2016**, 32, 6097-104	4	33
123	A miniaturized transient hot-wire device for measuring thermal conductivity of non-conductive fluids. *Microsystem Technologies*, **2016**, 22, 2463-2466	1.7	13
122	High thermosensitivity of silicon nanowires induced by amorphization. *Materials Letters*, **2016**, 177, 80-84	3.3	26
121	Environment-friendly carbon nanotube based flexible electronics for noninvasive and wearable healthcare. *Journal of Materials Chemistry C*, **2016**, 4, 10061-10068	7.1	90

120	3C-SiC on glass: an ideal platform for temperature sensors under visible light illumination. *RSC Advances*, **2016**, 6, 87124-87127	3.7	12
119	Flexible and multifunctional electronics fabricated by a solvent-free and user-friendly method. *RSC Advances*, **2016**, 6, 77267-77274	3.7	24
118	Influence of external mechanical stress on electrical properties of single-crystal n-3C-SiC/p-Si heterojunction diode. *Applied Physics Express*, **2015**, 8, 061302	2.4	9
117	Charge transport and activation energy of amorphous silicon carbide thin film on quartz at elevated temperature. *Applied Physics Express*, **2015**, 8, 061303	2.4	40
116	Graphite on paper as material for sensitive thermoresistive sensors. *Journal of Materials Chemistry C*, **2015**, 3, 8776-8779	7.1	80
115	Study on contact resistance in single-contact and multi-contact MEMS switches. *Microelectronic Engineering*, **2015**, 135, 13-16	2.5	5
114	Piezoresistive effect of p-type silicon nanowires fabricated by a top-down process using FIB implantation and wet etching. *RSC Advances*, **2015**, 5, 82121-82126	3.7	34
113	A survey of practical equations for prediction of effective thermal conductivity of spherical-particle nanofluids. *Journal of Molecular Liquids*, **2015**, 211, 712-733	6	45
112	The Piezoresistive Effect of SiC for MEMS Sensors at High Temperatures: A Review. *Journal of Microelectromechanical Systems*, **2015**, 24, 1663-1677	2.5	150
111	The effect of device geometry and crystal orientation on the stress-dependent offset voltage of 3C-SiC(100) four terminal devices. *Journal of Materials Chemistry C*, **2015**, 3, 8804-8809	7.1	23
110	The Dependence of Offset Voltage in p-Type 3C-SiC van der Pauw Device on Applied Strain. *IEEE Electron Device Letters*, **2015**, 36, 708-710	4.4	23
109	A Novel Three-State Contactless RF Micromachined Switch for Wireless Applications. *IEEE Electron Device Letters*, **2015**, 36, 1363-1365	4.4	8
108	Pseudo-Hall effect in single crystal 3C-SiC(111) four-terminal devices. *Journal of Materials Chemistry C*, **2015**, 3, 12394-12398	7.1	16
107	Micro cam system driven by electrostatic comb-drive actuators based on SOI-MEMS technology. *Microsystem Technologies*, **2015**, 21, 699-706	1.7	3
106	RF MEMS switches for smart antennas. *Microsystem Technologies*, **2015**, 21, 487-495	1.7	17
105	A planar fractal micro-transformer with air core and hilbert curve. *Microsystem Technologies*, **2015**, 21, 1691-1695	1.7	3
104	Graphite-on-paper based tactile sensors using plastic laminating technique **2015**,		8
103	Deformation of a floating liquid marble. *Soft Matter*, **2015**, 11, 4576-83	3.6	40

102	Micromachined Coreless Single-Layer Transformer Without Crossovers. *IEEE Magnetics Letters*, **2015**, 6, 1-4	1.6	8
101	Thermoresistive properties of p-type 3C-SiC nanoscale thin films for high-temperature MEMS thermal-based sensors. *RSC Advances*, **2015**, 5, 106083-106086	3.7	31
100	Orientation dependence of the pseudo-Hall effect in p-type 3C-SiC four-terminal devices under mechanical stress. *RSC Advances*, **2015**, 5, 56377-56381	3.7	24
99	The effect of strain on the electrical conductance of p-type nanocrystalline silicon carbide thin films. *Journal of Materials Chemistry C*, **2015**, 3, 1172-1176	7.1	27
98	Design and analysis of a z-axis tuning fork gyroscope with guided-mechanical coupling. *Microsystem Technologies*, **2014**, 20, 281-289	1.7	4
97	Piezoresistive Effect of p-Type Single Crystalline 3C-SiC Thin Film. *IEEE Electron Device Letters*, **2014**, 35, 399-401	4.4	42
96	Constrained Optimum Design of 3-DOF Microaccelerometers. *IETE Journal of Research*, **2014**, 60, 309-318	0.9	2
95	Thickness dependence of the piezoresistive effect in p-type single crystalline 3C-SiC nanothin films. *Journal of Materials Chemistry C*, **2014**, 2, 7176-7179	7.1	47
94	A fluid density sensor based on a resonant tube. *Advances in Natural Sciences: Nanoscience and Nanotechnology*, **2014**, 5, 035010	1.6	1
93	Electrical Properties of p-type 3C-SiC/Si Heterojunction Diode Under Mechanical Stress. *IEEE Electron Device Letters*, **2014**, 35, 1293-1295	4.4	27
92	Fundamental piezoresistive coefficients of p-type single crystalline 3C-SiC. *Applied Physics Letters*, **2014**, 104, 111905	3.4	59
91	J2240105 Development of MEMS Device for Tensile Testing of Nanowire-Shaped Specimens. *The Proceedings of Mechanical Engineering Congress Japan*, **2014**, 2014, _J2240105--_J2240105-	0	
90	Design of Metal MUMPs based LLC resonant converter for on-chip power supplies **2013**,		1
89	A micromirror with CNTs hinge fabricated by the integration of CNTs film into a MEMS actuator. *Journal of Micromechanics and Microengineering*, **2013**, 23, 075024	2	10
88	A micro gearing system based on a ratchet mechanism and electrostatic actuation. *Microsystem Technologies*, **2013**, 19, 261-267	1.7	4
87	Fabrication and testing of polymer cantilevers for VOC sensors. *Sensors and Actuators A: Physical*, **2013**, 202, 233-239	3.9	21
86	Design Optimization of MEMS Based LLC Tunable Resonant Converter for Power Supplies on Chip. *Advanced Materials Research*, **2013**, 705, 258-263	0.5	
85	A Novel Bidirectional Z-Shaped Thermally Actuated RF MEMS Switch for Multiple-Beam Antenna Array. *Advanced Materials Research*, **2013**, 705, 264-269	0.5	1

84	A novel electrothermally actuated RF MEMS switch for wireless applications **2013**,		2
83	Highly-sensitive fluorescence detection and imaging with microfabricated total internal reflection (TIR)-based devices. *Journal of Micro-Nano Mechatronics*, **2012**, 7, 45-59		2
82	Fabrication and analysis of high-performance piezoelectric MEMS generators. *Journal of Micromechanics and Microengineering*, **2012**, 22, 065017	2	35
81	Piezoelectric MEMS low-level vibration energy harvester with PMN-PT single crystal cantilever. *Electronics Letters*, **2012**, 48, 784	1.1	12
80	Development of polymer MEMS process technology as an approach to a sustainable production system. *Advances in Natural Sciences: Nanoscience and Nanotechnology*, **2012**, 3, 015009	1.6	7
79	Single mask, simple structure micro rotational motor driven by electrostatic comb-drive actuators. *Journal of Micromechanics and Microengineering*, **2012**, 22, 015008	2	4
78	Micromachined NH3 Gas Sensor with ppb-level Sensitivity Based on WO3 Nanoparticles Thinfilm. *Procedia Engineering*, **2011**, 25, 1149-1152		21
77	Longitudinal strain sensitive effect in a photonic crystal cavity. *Procedia Engineering*, **2011**, 25, 1357-1360		2
76	Real-time monitoring of Ca2+ concentration in pancreatic beta cells by a microfluidic device integrated with Total Internal Reflection (TIR)-based chip **2011**,		1
75	Strain Sensitive Effect in a Triangular Lattice Photonic Crystal Hole-Modified Nanocavity. *IEEE Sensors Journal*, **2011**, 11, 2657-2663	4	14
74	Investigation of strain sensing effect in modified single-defect photonic crystal nanocavity. *Optics Express*, **2011**, 19, 8821-9	3.3	43
73	Development and Analysis of a Sliding Tactile Soft Fingertip Embedded With a Microforce/Moment Sensor. *IEEE Transactions on Robotics*, **2011**, 27, 411-424	6.5	48
72	Multimodule Micro Transportation System Based on Electrostatic Comb-Drive Actuator and Ratchet Mechanism. *Journal of Microelectromechanical Systems*, **2011**, 20, 140-149	2.5	9
71	Novel fabrication process for a monolithic PMMA torsion mirror and vertical comb actuator. *Journal of Micromechanics and Microengineering*, **2011**, 21, 065032	2	9
70	Development of Fabrication Process for Large-Displacement Polymer MEMS with Stacked Movable Structures Based on Hot Embossing and Polishing. *Journal of Japan Institute of Electronics Packaging*, **2011**, 14, 507-512	0.1	
69	Nanostrain Sensing Based on Piezo-Optic Property of a Photonic Crystal Cavity. *IEEJ Transactions on Sensors and Micromachines*, **2011**, 131, 258-263	0.2	
68	Bulk PZT Thick Film Preparation on Silicon Wafer and its Application for MEMS Power Generator. *Materials Science Forum*, **2010**, 663-665, 1115-1120	0.4	1
67	Towards highly sensitive strain sensing based on nanostructured materials. *Advances in Natural Sciences: Nanoscience and Nanotechnology*, **2010**, 1, 045012	1.6	5

66	Micro/nano-mechanical sensors and actuators based on SOI-MEMS technology. *Journal of Family Business Management*, **2010**, 1, 013001	2.2	27
65	A novel micro transportation system with fast movement of a micro container based on electrostatic actuation and a ratchet mechanism. *Journal of Micromechanics and Microengineering*, **2010**, 20, 115026	2	5
64	Integration of SWNT film into MEMS for a micro-thermoelectric device. *Smart Materials and Structures*, **2010**, 19, 075003	3.4	20
63	Development of a miniaturized NO2 gas sensor based on nanoparticles WO3 thin film on interdigitated electrodes **2010**,		1
62	Measurement of mechanical and thermal properties of co-sputtered WSi thin film for MEMS applications. *Microsystem Technologies*, **2010**, 16, 1881-1886	1.7	0
61	Integrated CNTs thin film for MEMS mechanical sensors. *Microelectronics Journal*, **2010**, 41, 860-864	1.8	18
60	Evaluation and Analysis of Physical Properties of Nanomaterials for Highly Sensitive Mechanical Sensing Devices. *IEEJ Transactions on Sensors and Micromachines*, **2010**, 130, 146-151	0.2	1
59	Novel Three-Axis Solid-state Micro Accelerometer with Surrounding Beam Structure. *IEEJ Transactions on Sensors and Micromachines*, **2010**, 130, 242-246	0.2	0
58	Piezoresistive effect in silicon nanowires □A comprehensive analysis based on first-principles calculations **2009**,		5
57	Sensitivity enhancement of piezoresistive micro acceleration sensors with Nanometer Stress Concentration Regions on sensing elements **2009**,		3
56	Ultra miniature novel three-axis micro accelerometer **2009**,		5
55	Evaluation of the piezoresistive effect in single crystalline silicon nanowires **2009**,		5
54	Piezoresistive and thermoelectric effects of CNT thin film patterned by EB lithography **2009**,		1
53	Development of polymer electrostatic comb-drive actuator using hot embossing and ultraprecision cutting technology. *Journal of Micro/ Nanolithography, MEMS, and MOEMS*, **2009**, 8, 043065	0.7	7
52	Fabrication of optically smooth, through-wafer silicon molds for PDMS total internal reflection-based devices. *Microsystem Technologies*, **2009**, 15, 1845-1853	1.7	4
51	Versatile microfluidic total internal reflection (TIR)-based devices: application to microbeads velocity measurement and single molecule detection with upright and inverted microscope. *Lab on A Chip*, **2009**, 9, 244-50	7.2	20
50	Tangential and perpendicular driving micro transmission systems based on ratchet mechanism and electrostatic actuator **2009**,		2
49	Characterization of the piezoresistive effect and temperature coefficient of resistance in single crystalline silicon nanowires **2009**,		3

48	Development of a Monolithic PMMA Comb-Drive Micro Actuator Utilizing Hot Embossing and Ultra-Precision Machining **2009**,		1
47	A Monolithic Dual-Color Total-Internal-Reflection-Based Chip for Highly Sensitive and High-Resolution Dual-Fluorescence Imaging. *Journal of Microelectromechanical Systems*, **2009**, 18, 1371-1381	2.5	1
46	Developing a Wearable System with MEMS Accelerometer for Real-Time Activity Monitoring. *IEEJ Transactions on Sensors and Micromachines*, **2009**, 129, 142-147	0.2	1
45	Design and Fabrication of a Miniaturized Three-Degree-of-Freedom Piezoresistive Acceleration Sensor Based on MEMS Technology Using Deep Reactive Ion Etching. *Springer Proceedings in Physics* , **2009**, 377-383	0.2	0
44	Design and Simulation of Convective Inertial Sensor **2008**,		3
43	Micro Ratcheting Transmission Systems Based on Electrostatic Actuator **2008**,		2
42	Optimum design considerations for a 3-DOF micro accelerometer using nanoscale piezoresistors **2008**,		4
41	**2008**,		2
40	A multi axis fluidic inertial sensor **2008**,		18
39	Fabrication and Basic Characterization of a Piezoelectric Valveless Micro Jet Pump. *Japanese Journal of Applied Physics*, **2008**, 47, 8615-8618	1.4	24
38	Design and Simulation of Piezoresistive Micro Accelerometers for Wearable Sensing Applications **2008**,		1
37	Development of a 3-DOF Micro Accelerometer with Wireless Readout. *IEEJ Transactions on Sensors and Micromachines*, **2008**, 128, 235-239	0.2	4
36	Design and Simulation of a Novel 3-DOF MEMS Convective Gyroscope. *IEEJ Transactions on Sensors and Micromachines*, **2008**, 128, 219-224	0.2	15
35	Ultrahigh-sensitive WO3 nanosensor with interdigitated Au nano-electrode for NO2 detection. *Sensors and Actuators B: Chemical*, **2008**, 132, 234-238	8.5	48
34	Simulation and Fabrication of a Convective Gyroscope. *IEEE Sensors Journal*, **2008**, 8, 1530-1538	4	17
33	Development of a Flexible Thermopile Power Generator Utilizing BiTe-Cu Thin Films. *IEEJ Transactions on Sensors and Micromachines*, **2008**, 128, 352-357	0.2	
32	Development of a Dual-Axis Convective Gyroscope With Low Thermal-Induced Stress Sensing Element. *Journal of Microelectromechanical Systems*, **2007**, 16, 950-958	2.5	26
31	Fabrication and Characterization of 3-DOF Soft-Contact Tactile Sensor Utilizing 3-DOF Micro Force Moment Sensor. *IEEJ Transactions on Sensors and Micromachines*, **2007**, 127, 177-181	0.2	6

30	Optimization of PZT Diaphragm Pump for the Convective Gyroscope. *IEEJ Transactions on Sensors and Micromachines*, **2007**, 127, 347-352	0.2	2
29	Development of miniaturized 6-axis accelerometer utilizing piezoresistive sensing elements. *Sensors and Actuators A: Physical*, **2007**, 134, 310-320	3.9	55
28	Design, simulation and fabrication of a total internal reflection (TIR)-based chip for highly sensitive fluorescent imaging. *Journal of Micromechanics and Microengineering*, **2007**, 17, 1139-1146	2	14
27	Convective Gas Gyroscope Based on Thermo-Resistive Effect in Si P-N Junction **2007**,		5
26	A 2-DOF convective micro accelerometer with a low thermal stress sensing element. *Smart Materials and Structures*, **2007**, 16, 2308-2314	3.4	28
25	Design and fabrication process of a micropump using bulk Pb(Zr,Ti)O 3 for microfluidic devices **2007**, 6800, 439		
24	A micro transportation system (MTS) with large movement of containers driven by electrostatic comb-drive actuators. *Journal of Micromechanics and Microengineering*, **2007**, 17, 2125-2131	2	14
23	A Fully Integrated MEMS-Based Convective 3-DOF Gyroscope **2007**,		7
22	Design and Fabrication of a Convective 3-DOF Angular Rate Sensor **2007**,		1
21	Development of a Micro-Force/Moment Sensor Embedded Soft Fingertip and Its Experimental Verification by Compression Test. *Nippon Kikai Gakkai Ronbunshu, C Hen/Transactions of the Japan Society of Mechanical Engineers, Part C*, **2007**, 73, 3228-3233		0
20	Fabrication and Characterization of Smooth Si Mold for Hot Embossing Process. *IEEJ Transactions on Sensors and Micromachines*, **2007**, 127, 187-191	0.2	15
19	Novelmicro Transportation Systems Based on Ratchetmechanism and Electrostatic Actuators **2007**,		1
18	Straight movement of micro containers based on ratchet mechanisms and electrostatic comb-drive actuators. *Journal of Micromechanics and Microengineering*, **2006**, 16, 2532-2538	2	17
17	Simulation, fabrication and characterization of a three-axis piezoresistive accelerometer. *Smart Materials and Structures*, **2006**, 15, 1691-1699	3.4	21
16	Development of a dual-axis thermal convective gas gyroscope. *Journal of Micromechanics and Microengineering*, **2006**, 16, 1301-1306	2	46
15	**2006**,		2
14	Development of 4-DOF Soft-Contact Tactile Sensor and Application to Gripping Operation of Robotics Fingers **2006**,		1
13	Tactile Perception using Micro Force/Moment Sensor Embedded in Soft Fingertip **2006**,		3

12	Design and Fabrication of Polymer Electrostatic Comb-Drive Actuators for Micro Conveyer Systems. *IEEJ Transactions on Sensors and Micromachines*, **2006**, 126, 306-311	0.2	4
11	A Dual Axis Accelerometer Utilizing Low Doped Silicon Thermistor. *IEEJ Transactions on Sensors and Micromachines*, **2006**, 126, 190-194	0.2	6
10	Design and fabrication of a miniaturized six-degree-of-freedom piezoresistive accelerometer. *Journal of Micromechanics and Microengineering*, **2005**, 15, 1745-1753	2	23
9	Design and Fabrication of Six-Degree of Freedom Piezoresistive Turbulent Water Flow Sensor. *Journal of Sensor Science and Technology*, **2002**, 11, 191-199	0.3	
8	A MEMS-based microsensor to measure all six components of force and moment on a near-wall particle in turbulent flow		4
7	A silicon micromachined six-degree of freedom piezoresistive accelerometer		2
6	A dual axis thermal convective silicon gyroscope		5
5	Noise and frequency analyses of a miniaturized 3-DOF accelerometer utilizing silicon nanowire piezoresistors		1
4	Design & Fabrication of Piezoresistive Six Degree of Freedom Accelerometer for Biomechanical Applications		1
3	Micro force-moment sensor with six-degree of freedom		3
2	Six-degree of freedom micro force-moment sensor for application in geophysics		2
1	Underground LoRa Sensor Node for Bushfire Monitoring. *Fire Technology*,1	3	